

**Amendments to the Specification:**

**Please rewrite paragraph [0075] of the specification as follows:**

[0075] In the piezoelectric/electrostrictive film type actuators 11, 21 structured in this manner, when electricity is conducted between the even-numbered electrode film (lower electrode film 77 and upper electrode film 75) and the odd-numbered electrode film (intermediate electrode film 73) from below in the same manner as in the related art, an electric field function is generated in the respective piezoelectric/electrostrictive films 79. The electric field induced strain of the piezoelectric/electrostrictive film 79 is induced based on the electric field, and flexural displacement or force generation in a vertical direction are developed in the ceramic substrate 44 because of a lateral-transverse effect.